

10/539245
JC17 Rec'd PCT/PTO 16 JUN 2005

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of :
Tetsuji TOGAWA et al. : **Mail Stop: PCT**
Serial No. NEW : Attorney Docket No. 2005-0993A
Filed June 15, 2005 :

SUBSTRATE HOLDING MECHANISM,
SUBSTRATE POLISHING APPARATUS
AND SUBSTRATE POLISHING METHOD
[Corresponding to PCT/JP2003/017032
Filed December 26, 2003]

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Prior to examination of the above-referenced U.S. patent application please amend the application as follows:

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975